

# Hybrid ASP-based multi-objective scheduling of semiconductor manufacturing processes (Extended version)

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**Abstract.** Modern semiconductor manufacturing involves intricate production processes consisting of hundreds of operations, which can take several months from lot release to completion. The high-tech machines used in these processes are diverse, operate on individual wafers, lots, or batches in multiple stages, and necessitate product-specific setups and specialized maintenance procedures. This situation is different from traditional job-shop scheduling scenarios, which have less complex production processes and machines, and mainly focus on solving highly combinatorial but abstract scheduling problems. In this work, we address the scheduling of realistic semiconductor manufacturing processes by modeling their specific requirements using hybrid Answer Set Programming with difference logic, incorporating flexible machine processing, setup, batching and maintenance operations. Unlike existing methods that schedule semiconductor manufacturing processes locally with greedy heuristics or by independently optimizing specific machine group allocations, we examine the potentials of large-scale scheduling subject to multiple optimization objectives.

**Keywords:** Hybrid Answer Set Programming · Semiconductor manufacturing scheduling · Difference logic · Multi-objective optimization

## 1 Introduction

Scheduling semiconductor manufacturing processes imposes a complex challenge due to the variety of products, operations, and high-tech machines with diverse capabilities and characteristics. Effective scheduling aims at allocating jobs to machines in a manner that satisfies production needs, optimizes factory throughput, and guarantees punctual delivery [36]. In view of the steadily increasing demand [26], semiconductor manufacturers are forced to optimize their throughput, decrease cycle times, and enhance the on-time delivery of products to customers [30]. Corresponding approaches to provide decision support can be categorized into planning at the strategic level and operating a factory at the tactical or execution level. In this paper, we present an approach for scheduling realistic semiconductor manufacturing processes, taking multiple optimization objectives such as throughput or makespan as well as setup and batching criteria

into account. Our work builds on the recent SMT2020 simulation scenario [24], providing datasets that model the production processes of modern wafer fabs.

A typical wafer fabrication plant encompasses a variety of process flows, which are designated production routes for wafer lots within the factory. Each route consists of several hundred operations to be processed by machines belonging to about one hundred separate tool groups with specific functionalities and characteristics. To reduce the required investments into costly machines [24], constant utilization and idleness prevention are important process goals. Moreover, sophisticated process steps are iterated in several stages, which results in a re-entrant flow where wafer lots revisit machines in the same tool group multiple times. Hence, the manufacturing environment is different from traditional flow-shop and job-shop scenarios [16]. A crucial consequence of this re-entrant flow is that wafers at different stages in their manufacturing cycle can compete for the same machines, and dispatching strategies to resolve such competing demands have a noticeable impact on the overall production efficiency.

As a consequence of the complexity and dynamicity faced in practice, the wafer production is typically controlled by handcrafted [31] or machine-learned [38] dispatching rules at the execution level, or (re-)scheduling is localized to specific tool groups [29], e.g., for optimizing the allocation of lots queuing in front of a group of batching machines. While such local decision making approaches are tuned to specific fab settings, their scope is generally too narrow to guarantee overall efficiency in terms of optimization objectives. Unlike that, our work makes a step towards large-scale scheduling by modeling the production processes of a modern wafer fab, represented by the SMT2020 scenario, using Answer Set Programming (ASP) with difference logic [19,23]. We significantly extend our preliminary approach introduced in [3] and incorporate crucial features of realistic semiconductor fabs, including flexible machine processing, setup, batching and maintenance operations, as well as multiple optimization objectives reflecting the factory throughput, setup and batching criteria.

The paper is organized as follows. Section 2 surveys related literature on scheduling in traditional job-shop scenarios and particular challenges encountered in semiconductor manufacturing. In Section 3, we introduce the scheduling problem including crucial features of the SMT2020 scenario as well as the necessary background on ASP with difference logic. Our hybrid ASP with difference logic model enabling the large-scale scheduling of semiconductor manufacturing processes is presented in Section 4. In Section 5, we perform an experimental evaluation examining the potentials of large-scale scheduling subject to multiple optimization objectives. Section 6 concludes the paper with a brief summary and outlook on future work.

## 2 Literature review

Semiconductor fab scheduling is a highly complex task due to sophisticated production routes, diverse machine characteristics, and rapidly changing demands [14]. While lacking specific features of the semiconductor manufacturing process such as, e.g., re-entrant flow, batching, setup and maintenance operations, as well as varying processing times and sudden machine disruptions, the Flexible Job-Shop Scheduling Problem (FJSP) [6,34] along with the optimization methods devised for it are related approaches.

A wide range of techniques have been proposed in the literature to tackle combinatorial optimization for FJSP solving. Meta-heuristic algorithms incorporate local search methods, such as Genetic Programming [27,37], Tabu Search [27], Simulated Annealing [37], Harmony Search [33], Particle Swarm Optimization [22], and Ant Colony Optimization [39]. Exact solving methods are based on FJSP models in Mixed Integer Programming (MIP) [8,20,21], Constraint Programming (CP) [10,21], or ASP with difference logic [13,23].

Beyond FJSP, ASP [28] has been successfully used to schedule printing devices [4], specialist teams [32], work shifts [2], course timetables [5], medical treatments [11], and aircraft routes [35]. The hybrid framework of ASP with difference logic [23] particularly supports a compact representation and reasoning with quantitative resources like time, which has been exploited in domains such as lab resource [15], train connection [1], and parallel machine [12] scheduling, as well as for FJSP solving [13,23]. In this work, we extend our preliminary ASP with difference logic approach [3] to semiconductor fab scheduling with support for batching machines, partially flexible machine allocation strategies, and multi-objective optimization functionalities.

### 3 Background

This section briefly introduces the extensions of ASP by difference logic constraints and multi-shot solving functionalities, as well as our semiconductor manufacturing scheduling problem inspired by the SMT2020 simulation scenario.

#### 3.1 ASP with difference logic

We presuppose familiarity with the first-order modeling language of ASP, incorporating choice rules, aggregate atoms, as well as weak constraints for expressing objective function(s); see [7,17,28] for elaborate introductions. The hybrid framework of ASP with *difference logic constraints* [9] allows for expressions  $\&diff\{t_1 - t_2\} \leq t_3$  in the head of rules. With the exception of the constant 0, which denotes the number zero, the terms  $t_1$  and  $t_2$  represent *difference logic variables* that can be assigned integer values. If the body of a rule with  $\&diff\{t_1 - t_2\} \leq t_3$  in the head is satisfied, the difference  $t_1 - t_2$  must not exceed the integer constant  $t_3$ . That is, the difference logic constraints asserted by rules whose body is satisfied restrict the feasible values for difference logic variables, and the clingo[DL] system [23] extends clingo [17,18] by assuring the consistency of difference logic constraints imposed by an answer set.

In addition, we make use of *multi-shot ASP solving* [18], allowing for iterative reasoning processes by controlling and interleaving the grounding and search phases of clingo and clingo[DL]. For referring to a collection of rules to instantiate, `#program name(c). directives`, where `name` denotes a *subprogram* and the parameter `c` is a placeholder for some constant, e.g., an integer value, group the rules below them and enable their selective instantiation w.r.t. specific parameter values. Note that rules not preceded by any `#program` directive belong to an implicit, parameterless subprogram called `base`. Moreover, `#external h : b1, ..., bn.` statements are formed similar to rules, yet declare an atom `h` as *external* when the body `b1, ..., bn` is satisfied. Such an external

atom can be freely set to true or false via the Python interface of clingo or clingo[DL], so that rules containing  $h$  can be selectively (de)activated in order to control the search.

### 3.2 Semiconductor manufacturing scheduling

We consider a *Semiconductor Manufacturing Scheduling Problem* (SMSP) inspired by the SMT2020 simulation scenario. Given a set  $P$  of available *products* (the producible types of wafers), the production *route* for each product  $p \in P$  is a finite sequence  $p[1], \dots, p[n_p]$  of production *operations*, where  $n_p$  denotes the length of the production route for  $p$ . Each operation  $p[i]$  needs to be performed by some machine belonging to a *tool group*  $M(p[i])$  and requires a *setup*  $s(p[i]) \in \mathbb{N}$ , with  $s(p[i]) = 0$  indicating the special case that any (positive) setup can be in place when performing  $p[i]$ . Each setup  $s \in \mathbb{N}$  has an associated parameter  $\min(s) \in \mathbb{N}$  specifying a minimum number of production operations that should be processed by a machine before changing from  $s$  to another setup. Moreover, *batching* capacities for operations  $p[i]$  are expressed by the parameters  $\min(p[i]) \in \mathbb{N}$  and  $\max(p[i]) \in \mathbb{N}$ , denoting a minimum and a maximum batch size in terms of wafer lots. While the maximum batch size is a hard limit on the number of lots that can be processed simultaneously, the minima on batch size and setup changes reflect desiderata for a regular process flow but are not strictly necessary process limitations. Furthermore, each tool group  $M$  has associated *maintenance* operations  $c(M)$  and  $d(M)$ , which must be performed periodically based on the number of processed lots or accumulated processing time, respectively. That is, for each  $c \in c(M)$  (or  $d \in d(M)$ ), the parameters  $\min(c) \in \mathbb{N}$  and  $\max(c) \in \mathbb{N}$  (or  $\min(d) \in \mathbb{N}$  and  $\max(d) \in \mathbb{N}$ ) denote the minimum and maximum number of lots (or processing time) after which the maintenance operation has to be performed. Finally, for any production operation  $p[i]$ , setup  $s$ , and maintenance operation  $c$  or  $d$ ,  $\text{time}(p[i]) \in \mathbb{N}$ ,  $\text{time}(s) \in \mathbb{N}$ ,  $\text{time}(c) \in \mathbb{N}$  or  $\text{time}(d) \in \mathbb{N}$  provide the time required for performing the respective operation or changing to the machine setup, respectively.

The general properties above describe production routes and features of machines, and a set  $L$  of wafer lots represents the requested products, where each lot  $l \in L$  belongs to some product  $p(l) \in P$ . A *machine assignment*  $m(l[1]) \in M(p(l)[1]), \dots, m(l[n_{p(l)}]) \in M(p(l)[n_{p(l)}])$  determines a specific machine to perform each operation  $l[i]$  in the production route for a lot  $l$ . The *schedule* for a machine  $m$  in the tool group  $M$  is a finite sequence  $m[1], \dots, m[n_m]$  of sets of operations, where for each  $1 \leq j \leq n_m$ :

$$m[j] = \begin{cases} \{l_1[i], \dots, l_k[i]\} & \text{for lots } \{l_1, \dots, l_k\} \subseteq L \text{ with } p(l_1) = \dots = p(l_k) = p, \\ & i \leq n_p, m(l_1[i]) = \dots = m(l_k[i]) = m, k \leq \max(p[i]); \\ \{s\} & \text{for some setup } s > 0; \\ \{c\} & \text{for some maintenance operation } c \in c(M); \text{ or} \\ \{d\} & \text{for some maintenance operation } d \in d(M). \end{cases}$$

Starting from the initial machine setup  $s(m)[1] = 0$ , we define the successor setups for  $1 < j \leq n_m$  by  $s(m)[j] = \{s\}$  if  $m[j-1] = \{s\}$  indicates a change to the setup  $s \in \mathbb{N}$ , or  $s(m)[j] = s(m)[j-1]$  otherwise. Moreover, let  $l(m[j]) = \{l_1[i], \dots, l_k[i]\}$  if  $m[j] = \{l_1[i], \dots, l_k[i]\}$  for lots  $\{l_1, \dots, l_k\} \subseteq L$  whose  $i$ -th operation is processed

in batch, or  $l(m[j]) = \emptyset$  otherwise. The schedule for  $m$  is *feasible* if each  $l[i]$  with  $m(l[i]) = m$  belongs to exactly one set  $m[j]$  of operations, and for each  $1 \leq j \leq n_m$ :

- $s(m)[j] = s(p(l)[i])$  if  $s(p(l)[i]) > 0$  for some lot  $l \in L$  with  $l[i] \in l(m[j])$ ,
- $\sum_{\max(\{0\} \cup \{j_c < j \mid m[j_c] = \{c\}\}) < j' \leq j} |l(m[j'])| \leq \max(c)$  for each  $c \in c(M)$ ,
- $\min(c) \leq \sum_{\max(\{0\} \cup \{j_c < j \mid m[j_c] = \{c\}\}) < j' < j} |l(m[j'])|$  if  $m[j] = \{c\}$  for  $c \in c(M)$ ,
- $\sum_{\max(\{0\} \cup \{j_d < j \mid m[j_d] = \{d\}\}) < j' \leq j, l[i] \in l(m[j'])} (\text{time}(p(l)[i]) \div |l(m[j'])|) \leq \max(d)$  for each  $d \in d(M)$ , and
- $\min(d) \leq \sum_{\max(\{0\} \cup \{j_d < j \mid m[j_d] = \{d\}\}) < j' < j, l[i] \in l(m[j'])} (\text{time}(p(l)[i]) \div |l(m[j'])|)$  if  $m[j] = \{d\}$  for  $d \in d(M)$ .

That is, the required (positive) setup must be in place when performing a production operation, and the number of lots (or processing time) between maintenance operations  $c \in c(M)$  (or  $d \in d(M)$ ) must lie in the range  $[\min(c), \max(c)]$  (or  $[\min(d), \max(d)]$ ).

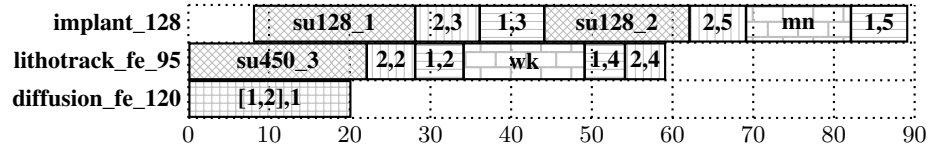
Given a feasible schedule for each machine  $m$ , for each  $1 \leq j \leq n_m$ , we denote the *operation time* of  $m[j]$  by  $o(m[j]) = \text{time}(p(l)[i])$  if there is some  $l[i] \in l(m[j])$ , or  $o(m[j]) = \text{time}(o)$  if  $m[j] \setminus l(m[j]) = \{o\}$ . Then, starting from  $o(m[0]) = 0$  and  $t(m[0]) = 0$ , the earliest *start time* of  $m[j]$  is

$$t(m[j]) = \max \left( \begin{array}{l} \{t(m[j-1]) + o(m[j-1])\} \cup \\ \{t(m'[j']) + o(m'[j']) \mid l[i] \in l(m[j]), 1 < i, l[i-1] \in l(m'[j'])\} \end{array} \right).$$

The start time  $t(m[j])$  thus reflects the earliest time at which  $m[j-1]$  is completed by machine  $m$  and the predecessor operations  $l[i-1]$  (if any) of all  $l[i] \in l(m[j])$  have been finished as well. Note that start times become infinite when the schedules for machines induce circular waiting dependencies between the production operations for lots, and we say that the (global) schedule of machine assignments for lots and feasible schedules for machines is *globally feasible* if all start times are finite.

The *makespan* of a globally feasible schedule is the maximum completion time  $t(m[n_m]) + o(m[n_m])$  over all machines  $m$ . An operation  $m[j_s] = \{s\}$  constitutes a *setup violation* for  $s \in \mathbb{N}$  if  $m[j] \in \mathbb{N}$  for some  $j > j_s$  indicates a setup change such that  $|\{j_s < j' < j \mid l(m[j']) \neq \emptyset\}| < \min(s)$ . Moreover,  $m[j]$  amounts to a *batch violation* if we have that  $|l(m[j])| < \min(p(l)[i])$  for some  $l[i] \in l(m[j])$ . The makespan, setup and batch violations provide optimization objectives to be minimized for globally feasible schedules.

For example, an (optimal) schedule for an SMSP instance is displayed in Figure 1. The machine in the *diffusion\_fe\_120* tool group is capable of batching and processes the first operation in the route of two lots of the same product simultaneously. Meanwhile, the setups *su450\_3* and *su128\_1*, required for sequential successor operations on machines in the tool groups *lithotrack\_fe\_95* and *implant\_128*, are brought in place before processing the second and third production operations for each lot. The machine in the *lithotrack\_fe\_95* group undergoes a maintenance operation labeled *wk* and then continues with the fourth operation in the production route for both lots. The fifth and last operation per lot is processed by the machine in the tool group *implant\_128*, where a switch to setup *su128\_2* as well as a maintenance operation labeled *mn* need to be performed in addition. The makespan 89 of this schedule is optimal, and likewise the setup and batch operations, the machine assignment of operations is fixed for simplicity, yet revisits of the *lithotrack\_fe\_95* and *implant\_128* machines illustrate re-entrant flow.



**Fig. 1.** The chart illustrates an optimal schedule for an example SMSP instance with two lots of the same product, indicated by the labels 1 and 2 followed by respective production operation numbers from 1 to 5. The production operations are performed by machines in three tool groups, called *implant\_128*, *lithotrack\_fe\_95*, and *diffusion\_fe\_120*, with 1 machine in each. The *diffusion\_fe\_120* machine starts by processing the first operation for the batch of both lots, while the remaining four operations per lot are performed sequentially by the *lithotrack\_fe\_95* and *implant\_128* machines. The *su450\_3*, *su128\_1*, and *su128\_2* slots indicate the equipping of machines with required setups, and the additional *wk* and *mn* slots denote maintenance operations.

## 4 Hybrid ASP encoding

In the following, we present our hybrid ASP with difference logic encoding of SMSP supplying multi-objective optimization functionalities. We start by describing the fact format of problem instances (Section 4.1), followed by static preallocation strategies to limit the number of assignable machines for each operation (Section 4.2), then the main encoding part to generate schedules incorporating batches, setup and maintenance operations (Section 4.3), and finally optimization by multi-shot ASP solving (Section 4.4).

### 4.1 Problem instance

The example SMSP instance for which an (optimal) schedule is shown in Figure 1 is represented by the facts in Listing 1. The structure of the used predicates is as follows:

`route( $p, i, g, t, m, n, s$ )`. The  $i$ -th operation for lots of product  $p$  takes the processing time  $t$  on a machine in tool group  $g$  equipped with the setup  $s$ , where  $m$  and  $n$  provide the minimum and maximum batch size. E.g., the fact in line 1 of Listing 1 states that the first operation for lots of product 1 needs to be performed by a machine in the *diffusion\_fe\_120* tool group, taking the processing time 20 for batches of (preferably) at least 2 and at most 4 lots with an arbitrary setup in view of  $s = 0$ .

`setup( $g, s, t, m$ )`. Changing to setup  $s \neq 0$  takes time  $t$  on machines of the tool group  $g$ , and at least  $m$  operations should be processed in the setup  $s$  before performing another setup change. The facts in lines 6 and 7 of Listing 1 express that the setups *su128\_1* and *su128\_2* need 20 or 18 time units, respectively, to be equipped on machines in the *implant\_128* tool group, where each of them ought to be maintained for 4 production operations at minimum before changing. Unlike that, the *su450\_3* setup, taking 22 units for equipping *lithotrack\_fe\_95* machines with it, can be changed freely, as declared by the fact in line 8.

`pm( $g, l, e, m, n, t$ )`. Machines in the tool group  $g$  need to undergo a periodic maintenance operation labeled  $l$ , whose type  $e$  is either `lots` or `time`, the parameters  $m$  and  $n$  specify a minimum and maximum amount of lots or processing time, respectively, after which the maintenance operation taking  $t$  time units needs to be repeated. The facts in lines 9-11 of Listing 1 specify one maintenance operation per tool group,

**Listing 1.** Facts for an SMSP instance with two lots and three tool groups with one machine each

```

1 route(1, 1, diffusion_fe_120, 20, 2, 4, 0).
2 route(1, 2, lithotrack_fe_95, 6, 1, 1, su450_3).
3 route(1, 3, implant_128, 8, 1, 1, su128_1).
4 route(1, 4, lithotrack_fe_95, 5, 1, 1, su450_3).
5 route(1, 5, implant_128, 7, 1, 1, su128_2).
6 setup(implant_128, su128_1, 20, 4).
7 setup(implant_128, su128_2, 18, 4).
8 setup(lithotrack_fe_95, su450_3, 22, 0).
9 pm(implant_128, implant_128_mn, lots, 2, 3, 13).
10 pm(lithotrack_fe_95, lithotrack_fe_95_wk, time, 12, 20, 15).
11 pm(diffusion_fe_120, diffusion_fe_120_mn, time, 125, 150, 35).
12 tool(implant_128, 1). tool(lithotrack_fe_95, 1). tool(diffusion_fe_120, 1).
13 lot(1, 1). lot(2, 1).

```

where *implant\_128\_mn* is based on processed lots, while *lithotrack\_fe\_95\_wk* and *diffusion\_fe\_120\_mn* need to be repeated according to accumulated processing times.

`tool(g, l)`. A machine labeled *l* belongs to the tool group *g*, where the facts in line 12 of Listing 1 introduce one machine per tool group.

`lot(l, p)`. A lot labeled *l* of product *p* needs to be produced, and two lots of the (single) product 1 are declared by the facts in line 13 of Listing 1.

## 4.2 Partially flexible machine assignment

Experiments with our prototypical SMSP encoding [3] showed that fixing the machine assignment of operations upfront sacrifices optimality, while a fully flexible assignment leads to plenty ground rules slowing down the optimization when a tool group contains many machines. To enable trade-offs between the fixed and fully flexible machine allocation strategies, the novel encoding part in Listing 2 introduces a constant `sub_size` that allows for limiting the number of assignable machines per operation. That is, when `sub_size` is 0, the machine assignment remains fully flexible, gets fixed if the value is 1, or is limited to some *subgroup* of a tool group with at most `sub_size` many machines for values greater than one. In the latter case, the rule in lines 10-12 partitions  $N$  machines of a tool group  $G$  into  $\lceil N \div \text{sub\_size} \rceil$  many subgroups, each gathering `sub_size` or `sub_size - 1` of the machines in  $G$  when  $N \geq \text{sub\_size}$ . For example, we derive the atoms `subgroup(implant_128,1,1,3)`, `subgroup(implant_128,2,4,5)`, and `subgroup(implant_128,3,6,7)` by the rule in lines 13-14, giving the subgroups  $\{1, 2, 3\}$ ,  $\{4, 5\}$ , and  $\{6, 7\}$  when seven machines in the *implant\_128* tool group are partitioned for the `sub_size` value 3.

The rules in lines 18-24 determine the subgroup to which an operation is allocated, based on a lexicographical index for operations to be processed by machines in the same tool group. This allocation can be configured by the constant `lot_step`: if its value is 0, all operations of a lot are mapped to a common index, or to successive indexes in case of value 1. The rationale for these two strategies is that operations performed on the same lot succeed one another and will thus never compete for a machine. On the other hand, the operations may require different setups so that changes are needed when reusing the same machine. In fact, the latter indexing strategy is likely to map operations of a lot to separate subgroups, as the rule in lines 23-24 allocates them in a round robin fashion.

**Listing 2.** Encoding part for partitioning tool groups into subgroups and preallocation by setups

```

1 #const sub_size = 0. % if "sub_size" is positive, it limits machines in subgroups
2 #const lot_step = 0. % if "lot_step" is set to 1, operations of lot get separated
3 #const by_setup = 0. % if "by_setup" is set to 1, operation setups get subdivided
4
5 % split tool groups into subgroups of at most "sub_size" many machines in each
6
7 subgroup_size(sub_size) :- sub_size > 0.
8
9 subgroup(G, 1, M) :- tool(G, M), sub_size = 0.
10 subgroup(G, J, M) :- tool(G, N), subgroup_size(S), not tool(G, N+1),
11 J = 1 .. K, K = (N+S-1)/S, L = (N\K+J-|N\K-J|)/2,
12 M = (J-1)*(N/K)+(L+J-1-|L-J+1|)/2+1 .. J*(N/K)+L.
13 subgroup(G, J, M1, M2) :- subgroup(G, J, M1), not subgroup(G, J, M1-1),
14 subgroup(G, J, M2), not subgroup(G, J, M2+1).
15
16 % map each production operation to some subgroup of the respective tool group
17
18 step_index(G, K, (L, P, I, T, S)) :- lot(L, P), route(P, I, G, T, M, N, S),
19 K = #count{P', L', I' * lot_step : lot(L', P'),
20 route(P', I', G, T', M', N', S'),
21 (P', L', I' * lot_step) < (P, L, I * lot_step)}.
22
23 step_subgroup(G, K\J+1, O) :- step_index(G, K, O),
24 subgroup(G, J, _), not subgroup(G, J+1, _).
25
26 assignable(O, G, M) :- step_subgroup(G, J, O), subgroup(G, J, M), by_setup = 0.
27
28 % distinguish machines in each subgroup based on production operations' setups
29
30 subgroup_setup(G, J, S) :- step_subgroup(G, J, (L, P, I, T, S)), by_setup != 0.
31 subgroup_setup(G, J, S, N) :- subgroup_setup(G, J, S),
32 N = #sum+{T, L, P, I : step_subgroup(G, J, (L, P, I, T, S))}.
33
34 setup_index(G, J, K, S, N) :- subgroup_setup(G, J, S, N),
35 K = #count{S', N' : subgroup_setup(G, J, S', N'), (N, S) < (N', S')}.
36 setup_index(G, J, K, N) :- setup_index(G, J, K, S, N).
37 setup_index(G, J, K) :- setup_index(G, J, K-1, _),
38 not setup_index(G, J, K, _).
39
40 setup_machine(G, J, M, M\K, N) :- subgroup(G, J, M1, M2), setup_index(G, J, K),
41 setup_index(G, J, M\K, N), M = 0 .. M2-M1.
42 setup_machine(G, J, M, K, A+N) :- subgroup(G, J, M1, M2), setup_index(G, J, K, N),
43 next_machine(G, J, M2-M1, K-1, A, M).
44
45 %* [...] *%
46
47 assignable((L, P, I, T, S), G, M1+M) :- step_subgroup(G, J, (L, P, I, T, S)),
48 setup_machine(G, J, M, K, A),
49 setup_index(G, J, K, S, N),
50 subgroup(G, J, M1, M2).

```

As subordinate machine allocation criterion within each subgroup, the setups of operations can be inspected by means of the rules in lines 30-50 when the constant `by_setup` is set to a value other than 0. The idea of the rules in lines 30-38 is to order setups by the sum of processing times for their operations, where setups requiring more processing time come first. Then the rules in lines 40-50 follow this order to map setups and the respective operations to specific machines, always picking the machine with the least load so far for the next setup to allocate. The rules to determine the least loaded machine for a setup are omitted in Listing 2 to save space, and our full encoding is available online.<sup>4</sup> For example, if two machines of the *implant\_128* tool

<sup>4</sup><https://github.com/prosysscience/FJSP-SMT2020>



group belong to the same subgroup for the lots specified by the facts in Listing 1, the allocation by setups yields the atoms `assignable((1,1,3,8,su128_1),implant_128,1)`, `assignable((2,1,3,8,su128_1),implant_128,1)`, `assignable((1,1,5,7,su128_2),implant_128,2)`, and `assignable((2,1,5,7,su128_2),implant_128,2)`, thus mapping the third operation in the route of both lots, requiring the setup `su128_1`, to the first and the fifth operation for both with the setup `su128_2` to the second machine of the subgroup.

### 4.3 Schedule generation

While the previous encoding part specifies preallocation strategies to statically limit the machines to which each operation may be assigned, Listing 3 describes the actual, combinatorial scheduling task, including the machine assignment, setup and maintenance operations, as well as the aggregation of *batches*. The latter feature was not yet incorporated in our prototypical SMSP encoding [3] and is newly introduced by the rules in lines 54-64. To begin with, (ordered) pairs of operations processed by machines with a maximum batch size beyond one are determined in lines 54-58. Then, batches are generated by applying the choice rule in line 60, which represents batch processing of the first operation for both lots given by the facts in Listing 1 in terms of the derivable atom `batch(diffusion_fe_120,(1,1,1,20,0),(2,1,1,20,0))`. That is, a batch is identified by the operation on its lexicographically smallest lot, to which lots with greater identifiers are linked via the `batch/3` predicate. Any such linked lots are indicated by `batched/1`, and `batched/2` provides a symmetric version of `batch/3`, where both of the `batched` predicates are derived by the rule in line 63. The integrity constraint in line 64 makes sure that batches partition the lots of a product, as it rules out that the lot identifying a batch is itself linked to another (lexicographically smaller) lot. This unambiguous batch representation is exploited by the integrity constraint in line 61, where it suffices to count the linked lots to assert that the maximum batch size for an operation is not exceeded.

The choice rule in line 68 continues with the *machine assignment* by selecting exactly one machine, among those determined by a preallocation strategy from the previous subsection, for processing an operation. Operation pairs assigned to the same machine are brought into an ordered representation in terms of the `step_assign/3` predicate via the rules in lines 70-71. These pairs are filtered in lines 72-73 to indicate the operations on different lots by `lots_assign/3`. Only for the latter an execution order needs to be guessed by applying the rules in lines 77-78, provided that the operations do not belong to the same batch, which is checked in line 74. However, the operations in a batch must share a common machine, as asserted by the integrity constraint in line 75.

The execution order of operations sharing a machine must be inspected further to allocate required *setup and maintenance* operations. As several kinds of periodic maintenance may need to be applied to machines of the same tool group and their durations add up when they are performed in sequence, the rules in lines 82-84 associate maintenance operations with (positive) indexes in decreasing order of their durations, with the additional index `0` used for operation setups other than (don't care) setup `0`. E.g., the facts in Listing 1 yield the atoms `main_setup(implant_128,implant_128_mn,1,13)`, `main_setup(implant_128,su128_1,0,20)`, and `main_setup(implant_128,su128_2,0,18)` in view of the periodic *mn* maintenance along with the `su128_1` and `su128_2` setups of

**Listing 3.** Encoding part to assign batches, machines, as well as setup and maintenance operations

```

52 % generate batches for operations of different lots with same product in subgroups
54 step_batch(G, J, M, N, (L, P, I, T, S)) :-
55     step_subgroup(G, J, (L, P, I, T, S)), route(P, I, G, T, M, N, S), 1 < N.
56 lots_batch((L1, P, I, T, S), (L2, P, I, T, S)) :-
57     step_batch(G, J, M, N, (L1, P, I, T, S)),
58     step_batch(G, J, M, N, (L2, P, I, T, S)), L1 < L2.
60 {batch(G, O1, O2) : lots_batch(O1, O2)} 1 :- step_batch(G, J, M, N, O2).
61 :- step_batch(G, J, M, N, O1), N #count{O2 : batch(G, O1, O2)}.
63 batched(O1, O2; O2, O1; O2) :- batch(G, O1, O2).
64 :- batched(O1), batch(G, O1, O2).
66 % generate assignment of production operations to machines and order of processing
68 {assign(O, G, M) : assignable(O, G, M)} = 1 :- step_index(G, K, O).
70 step_pair(G, O1, O2) :- assignable(O1, G, M), assignable(O2, G, M), O1 < O2.
71 step_assign(G, O1, O2) :- step_pair(G, O1, O2), assign(O1, G, M), assign(O2, G, M).
72 lots_assign(G, O1, O2) :- O1 = (L1, P1, I1, T1, S1), step_assign(G, O1, O2),
73     O2 = (L2, P2, I2, T2, S2), (L1, P1) < (L2, P2).
74 in_sequence(G, O1, O2) :- lots_assign(G, O1, O2), not batch(G, O1, O2).
75 :- batch(G, O1, O2), not lots_assign(G, O1, O2).
77 {lots_order(G, O1, O2)} :- in_sequence(G, O1, O2).
78 lots_order(G, O2, O1) :- in_sequence(G, O1, O2), not lots_order(G, O1, O2).
80 % determine setup and maintenance operations required before production operations
82 main_setup(G, H, K, W) :- pm(G, H, E, M, N, W),
83     K = #count{H' : pm(G, H', E', M', N', W')}, (W, H) <= (W', H').
84 main_setup(G, S, 0, U) :- setup(G, S, U, M).
86 step_order(G, O1, O2) :- main_setup(G, X, K, V), lots_order(G, O1, O2).
87 step_order(G, O1, O2) :- main_setup(G, X, K, V), step_assign(G, O1, O2),
88     O1 = (L, P, I1, T1, S1), O2 = (L, P, I2, T2, S2).
90 %* [...] *%
92 equip(O, G, S) :- setup(G, S, U, M), step_index(G, K, O), O = (L, P, I, T, S),
93     not reuse(G, O).
95 {maintain(O, G, H)} :- pm(G, H, E, M, N, W), step_index(G, K, O).
96 :- batched(O1, O2), maintain(O1, G, H), not maintain(O2, G, H).
97 :- pm(G, H, E, M, N, W), step_index(G, K, O), not step_order(G, _, O),
98     not maintain(O, G, H).
100 %* [...] *%
102 delay(O, G, 0, U) :- main_setup(G, S, 0, U), equip(O, G, S).
103 delay(O, G, 0, U+V) :- main_setup(G, S, 0, U), equip(O, G, S), delay(O, G, 1, V).
104 delay(O, G, K, W) :- main_setup(G, H, K, W), maintain(O, G, H), 0 < K.
105 delay(O, G, K, W+V) :- main_setup(G, H, K, W), maintain(O, G, H), 0 < K,
106     delay(O, G, K+1, V).
107 delay(O, G, K-1, V) :- delay(O, G, K, V), 0 < K.

```

operations processed by machines in the *implant\_128* tool group. For tracking the exact execution order of operations on a machine, also if they involve the same lot, the `step_order/3` predicate determined by the rules in lines 86-88 augments the guessed predicate `lots_order/3` with atoms reflecting the production route of a lot revisiting the same machine. While we omit the details to save space, let us mention that the necessity of a setup change before performing an operation is a consequence of the execution sequence on a machine, i.e., the rule in lines 92-93 derives an atom of the

`equip/3` predicate whenever the setup required for an operation is not already in place. Unlike that, maintenance procedures are subject to a range, either in terms of processed lots or accumulated processing time, after which they have to be repeated. Hence, the rule in line 95 introduces the choice to perform a specific maintenance before the next production operation, the integrity constraint in line 96 distributes such a choice over all lots in a batch, and (auxiliary) maintenances before the first production operation on a machine are asserted in lines 97-98. The resulting maintenance and setup times needed before the next production operation can be processed are then added up by the rules in lines 102-107, where additional rules and constraints ensuring the compliance of maintenance procedures to the specified repetition ranges are part of our full encoding.<sup>4</sup> For example, the *mn* maintenance performed before the fifth operation for lot 1 in Figure 1 is expressed by the atoms `delay((1,1,5,7,su128_2),implant_128,1,13)` and `delay((1,1,5,7,su128_2),implant_128,0,13)`, the latter providing 13 as the sum of all maintenance and setup times required before the production operation can be processed.

#### 4.4 Multi-objective optimization

Our multi-objective optimization approach combines minimization at the level of difference logic variable values, as already used in [3,13], with native ASP optimization capacities, as applied in [1,12,15] w.r.t. the satisfaction of difference logic constraints, by means of multi-shot solving functionalities [18]. To this end, the rules in lines 111-124 of Listing 4 assert difference logic constraints on the completion times of operations, beginning with processing times of the first operations in production routes (lines 111-112) or processing plus setup times (lines 113-114) for all operations to which the latter apply. These lower bounds are propagated along the production route of each lot (lines 117-118) and the processing order of operations on machines (lines 119), where the times required for maintenance and setup are incorporated in addition (lines 120-121). Notably, batches are handled by synchronizing the completion time between the operations on involved lots in line 116, so that the predecessor operation (if any) finishing latest among all lots in the batch is decisive for the entire batch. The rule in lines 123-124 asserts the completion time of the last operation in each lot's production route as a lower bound on the difference logic variable `makespan`, thus enabling plain *makespan minimization* by supplying `--minimize-variable=makespan` as an option to `clingo[DL]`.

However, to incorporate the minimization of *setup and batch violations* as additional optimization criteria beyond *makespan*, we utilize a custom control script on top of the Python interface of `clingo[DL]`. Its first stage concerns *makespan* minimization, where the `opt(b)` subprogram in lines 128-131 of Listing 4 is instantiated with the value  $t - 1$  for the parameter `b` and then solved with the external atom `bound(t - 1)` set to true whenever an answer set such that `makespan = t` has been found. This makes sure that each answer set provides a schedule with strictly shorter *makespan* until an unsatisfiable solving attempt yields that the *makespan*  $t$  of the last schedule is optimal. In the latter case, the subprogram `weak(b)` in lines 133-142 gets instantiated with the value  $t$  for `b` (and possibly also `opt(b)` if the value  $t$  has not been supplied for `b` before), which fixes the *makespan* of any subsequently found schedule to the optimum  $t$ . With the weak constraints in lines 138-142 as well as the rule in line 136 at hand for indicating operations whose setup is reinstalled after some temporary change, the second stage consists

**Listing 4.** Encoding part for determining lot completion times and multi-objective optimization

```

109 % assert difference logic constraints on completion times of production operations
111 &diff{0 - (L, P, 1, T, S)} <= -T :- step_index(G, K, (L, P, 1, T, S)),
112                                not setup(G, S, _, _).
113 &diff{0 - (L, P, I, T, S)} <= -T-U :- step_index(G, K, (L, P, I, T, S)),
114                                    setup(G, S, U, M).

116 &diff{O1 - O2} <= 0 :- batched(O1,O2).
117 &diff{O1 - O2} <= -T :- step_index(G1, K1, O1), O1 = (L, P, I, T1, S1),
118                        step_index(G2, K2, O2), O2 = (L, P, I+1, T, S).
119 &diff{O1 - O2} <= -T :- lots_order(G, O1, O2), O2 = (L, P, I, T, S).
120 &diff{O1 - O2} <= -T-V :- step_order(G, O1, O2), O2 = (L, P, I, T, S),
121                        delay(O2, G, 0, V).

123 &diff{0 - makespan} <= 0 :- step_index(G, K, O),
124                            O = (L, P, I, T, S), not route(P, I+1, _, _, _, _).

126 % subprograms for minimizing the makespan, setup and batch violations of schedules

128 #program opt(b).
129 #external bound(b).

131 &diff{makespan - 0} <= b :- bound(b).

133 #program weak(b).
134 bound(b).

136 change(G, O) :- change(G, O, O1).

138 ~ setup(G, S, U, M), equip(O, G, S), change(G, O),
139   #count{O2 : reuse(G, O, O2), not batched(O2)} < M-1. [1@2, O]

141 ~ step_batch(G, J, M, N, O), not batched(O),
142   #count{O2 : batch(G, O, O2)} M-2. [1@1, O]

```

of native ASP optimization for minimizing setup and batch violations. Here we take setup violations, where a setup gets changed before performing the intended minimum number of production operations using it, as strictly more significant (optimization level @2) than violations of the minimum batch size (optimization level @1), considering that equipping a machine with a setup takes extra time and effort. For example, the schedule in Figure 1 involves one setup violation due to changing from the setup *su128\_1* to *su128\_2* before performing the intended minimum number of four operations with this setup on the *implant\_128* machine. Since avoiding the setup violation would require a second machine in the *implant\_128* tool group, the schedule is nevertheless optimal.

## 5 Experiments

We constructed a scalable set of benchmark instances, focusing on sub-routes of 10 production operations for two product types from the SMT2020 simulation scenario [24]. The 10 operations in both sub-routes are processed by machines belonging to three tool groups and do thus involve re-entrant flow, as a lot visits the same tool group multiple times. Moreover, the operations incorporate batching and specific setups, and machines undergo periodic maintenance operations. In the following, we concentrate on instances with 9 machines, i.e., 3 per tool group, and gradually increasing number of lots. Further smaller- and larger-scale instances along with our implementation are available online.<sup>4</sup>

**Table 1.** Preallocation strategy results with 3 machines per tool group and 10 operations per lot

9 Machines		70 Operations		80 Operations		90 Operations		100 Operations	
Size		Lot	Step	Lot	Step	Lot	Step	Lot	Step
<b>Fixed</b>	Makespan	483	428	489	440	486	531	592	<b>553</b>
	1 Setup/Batch	6/12	2/12	5/14	0/13	5/14	3/12	3/12	0/16
	1 st/2 nd Stage	2/1	TO/27	6/2	TO/13	11/13	TO	TO/78	TO
<b>Flexible</b>	Makespan	483	475	592	592	592	539	745	698
	2 Setup/Batch	2/8	0/9	1/8	1/8	1/10	0/11	0/12	0/15
	1 st/2 nd Stage	5/1	TO	TO/114	TO/1	TO/130	TO	TO	TO
<b>Setup</b>	Makespan	559	–	815	–	1357	–	1486	–
	3 Setup/Batch	0/8	–	0/8	–	0/10	–	10/18	–
	1 st/2 nd Stage	TO	–	TO/140	–	TO/79	–	TO	–
<b>Setup</b>	Makespan	483	475	592	592	592	536	745	683
	2 Setup/Batch	2/8	0/9	1/8	1/8	1/10	0/12	0/13	0/16
	1 st/2 nd Stage	2/1	TO	TO/21	TO/25	TO/22	TO	TO/76	TO
<b>Setup</b>	Makespan	<b>334</b>	–	<b>345</b>	–	<b>434</b>	–	555	–
	3 Setup/Batch	0/8	–	0/8	–	0/11	–	0/12	–
	1 st/2 nd Stage	TO/20	–	TO/123	–	TO	–	TO/73	–

We ran our experiments with clingo[DL] (version 1.4.0) on an Intel® Core™i7-8650U CPU Dell Latitude 5590 machine under Windows 10, imposing two time limits per run: the first stage for makespan minimization is aborted at 450 seconds, in which case the best schedule found so far is taken as upper bound on the makespan for proceeding to minimize setup and batch violations with another 150 seconds time limit.

Table 1 reports the quality of best schedules obtained within the time limits for both optimization stages, split into ‘Makespan’ and ‘Setup/Batch’ values, while two runtimes or ‘TO’ for a timeout, respectively, are given in the ‘1 st/2 nd Stage’ rows, only listing a single ‘TO’ entry in case both stages timed out. The ‘Size’ column provides the value taken for the constant `sub_size`, limiting the number of machines in subgroups to which the operations are preallocated. For the latter, the ‘Lot’ columns include results with value 0 for the constant `lot_step`, where a common subgroup takes all operations for a lot, or for value 1 in the ‘Step’ columns, leading to their distribution among subgroups.

The ‘Size’ value 1 necessarily leads to a fixed machine assignment, for which the quality indicators clearly show that the ‘Step’ strategy yields better schedules, although it incurs more timeouts and thus fewer certain optima because operations on different lots increase the flexibility of execution sequences and thus search complexity. While flexibility within subgroups by setting their ‘Size’ to 2 or 3 in principle allows for improved schedules, we observe a deterioration due to sharply increasing instantiation size and search effort, as already observed in [3]. The setup strategy to differentiate operations and machines within subgroups, activated by changing the constant `by_setup`, aims to cut down the scheduling complexity in line with the optimization objectives by reducing the need for setup changes. This leads to significantly improved schedules with ‘Size’ 3, where the ‘Lot’ and ‘Step’ preallocation strategies are indifferent and redundant results for the latter are omitted, up to a critical size reached with 100 operations.

With our preliminary approach [3], using a more naive and less feature-rich encoding of either fixed or fully flexible machine assignments, the threshold at which problem size and combinatorics get prohibitive was reached at less than 50 operations already. Despite gearing up to double that size, our benchmark instances still represent small excerpts of the large-scale semiconductor fabs with more than 100 tool groups and from 242 to 543 production operations per lot modeled by [24]. The elevated complexity in comparison to basic settings like the traditional FJSP is mainly due to sophisticated

setup and maintenance operations, requiring a detailed analysis of execution sequences on machines for SMSP. We conjecture that similar scalability limits would also be encountered with MIP or CP encodings, yet the first-order modeling language of ASP with difference logic facilitates rapid prototyping and experimentation. In fact, our performance evaluation aims to explore the feasibility of search and optimization, in order to come up with strategies for breaking down large SMSP instances into more manageable portions, e.g., focusing on some bottleneck tool groups or re-entrant flow of operations.

## 6 Conclusion

This work extends our preliminary SMSP approach [3] with crucial features, namely, scalable and informed preallocation strategies to reduce the instantiation size and search complexity, as well as batch processing and multiple optimization objectives. While we enhance the scheduling scalability and coverage of real-world features, our mid-term goal is to incorporate scheduling into the real or simulated management of semiconductor manufacturing processes. As next step into this direction, we aim to use scheduling for improving the decision making in the PySCFabSim simulator [25], where methods available so far, i.e., handcrafted dispatching rules or black-box machine learning models, function locally and do not take the global impact of their decisions into account.

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